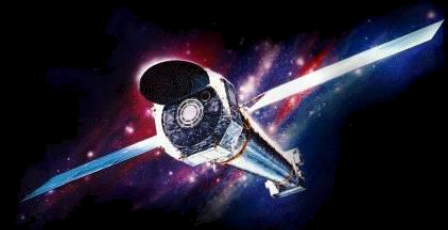


# Modeling contamination migration on the Chandra X-ray Observatory — III

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Catherine Grant, Herman Marshall, Alexey Vikhlinin,  
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Universities Space Research Association  
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Northrop Grumman



# Outline



- Introduction
- Molecular contamination on ACIS filters
- Thermal model for ACIS cavity
- Molecular transport simulations
- Summary



# Chandra's Advanced CCD Imaging Spectrometer (ACIS)



## ➤ ACIS cavity

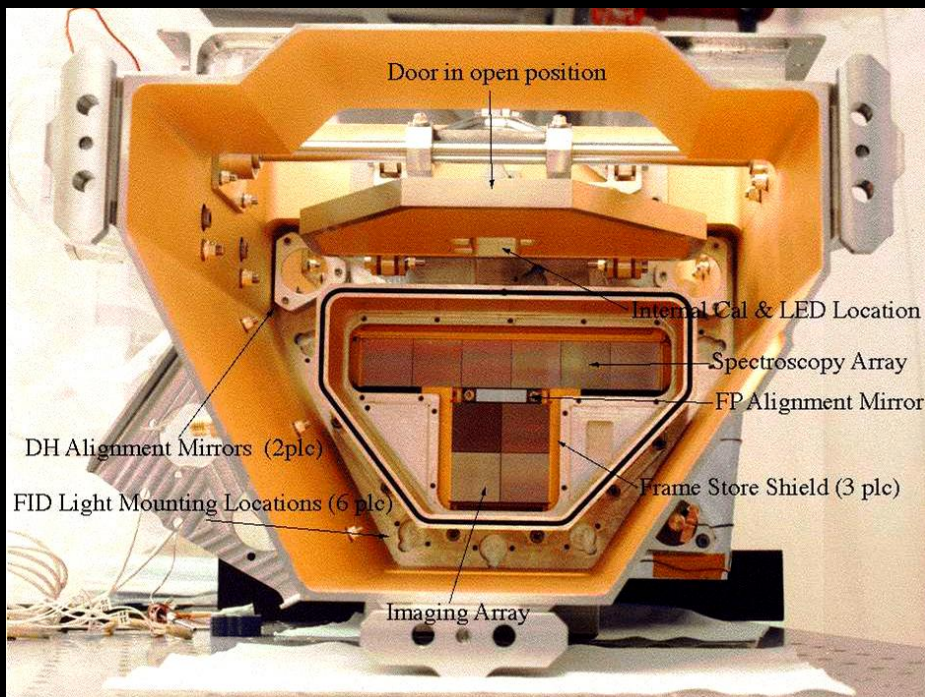
- ❑ Collimator
- ❑ Snoot & door
- ❑ Camera top & filters (OBF)

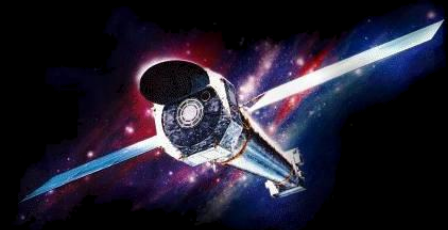
## ➤ ACIS operating temperatures

- ❑ Focal plane  $T_{FP} = -120^{\circ}\text{C}$
- ❑ Camera housing  $T_{DH} = -60^{\circ}\text{C}$ 
  - $\approx 8^{\circ}\text{C}$  colder with heaters off
- ❑ Optical blocking filters  $T_{OBF}$ 
  - $\approx T_{DH} \approx -60^{\circ}\text{C}$  near OBF edge
  - $5\text{--}20^{\circ}\text{C}$  warmer near center depending on emissivity  $\epsilon_{OBF}$

## ➤ Contamination on cold OBFs

- ❑ Mass column  $\approx 200 \mu\text{g cm}^{-2}$ .
  - $\leq 1 \text{ g}$  in entire *Chandra* optical cavity (calculated)
  - $\approx 30 \times$  pre-flight estimates
- ❑ Thicker near OBF edge





# Contamination-migration simulations for Chandra



## ➤ 2004 (I)

- ❑ Low-resolution geometrical model for ACIS cavity
- ❑ Supported bake-out decision in 2004

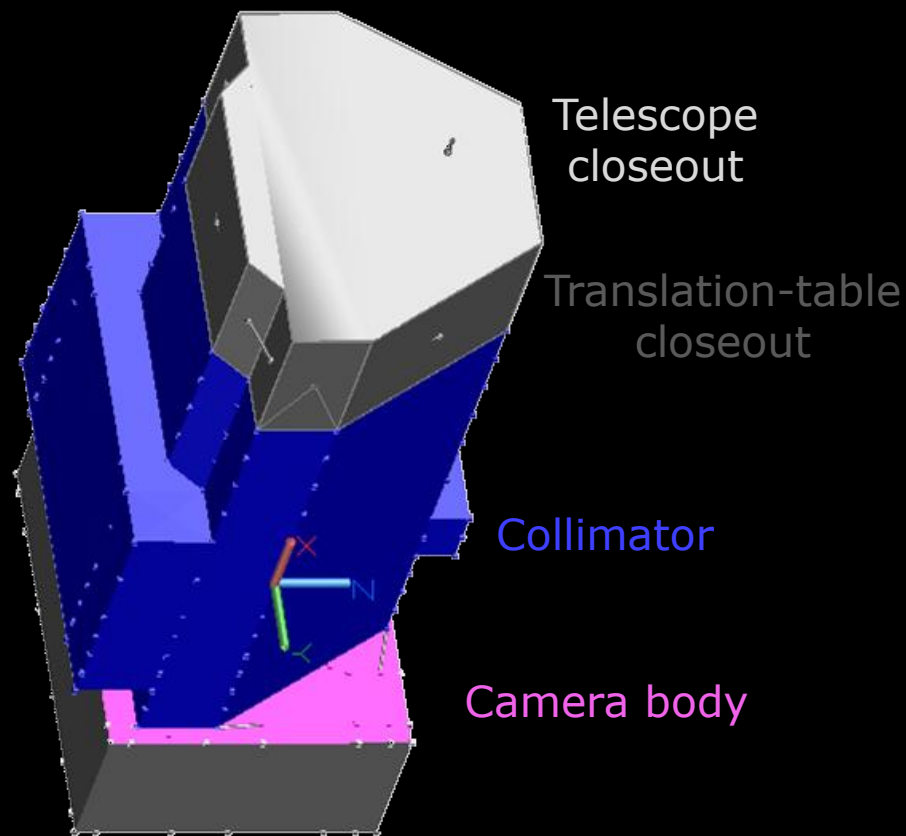
## ➤ 2013 (II)

- ❑ High-resolution geometrical model for ACIS cavity
- ❑ Higher emissivity for contaminated surfaces

## ➤ 2015 (III)

- ❑ Same model as 2013
- ❑ Will support bake-out decision in 2016

## ➤ ACIS geometrical model (exterior view)





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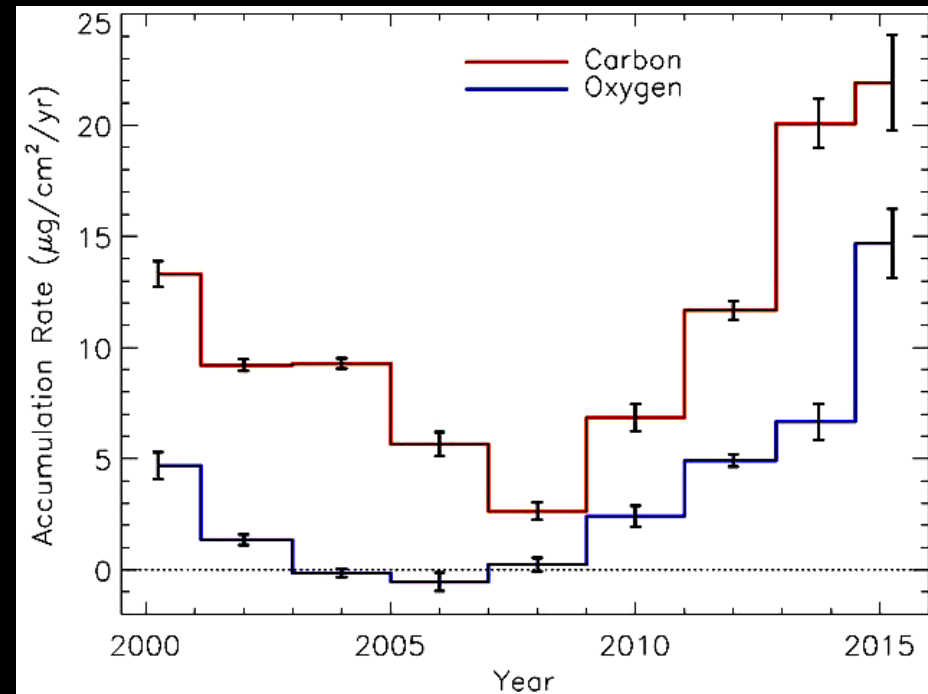
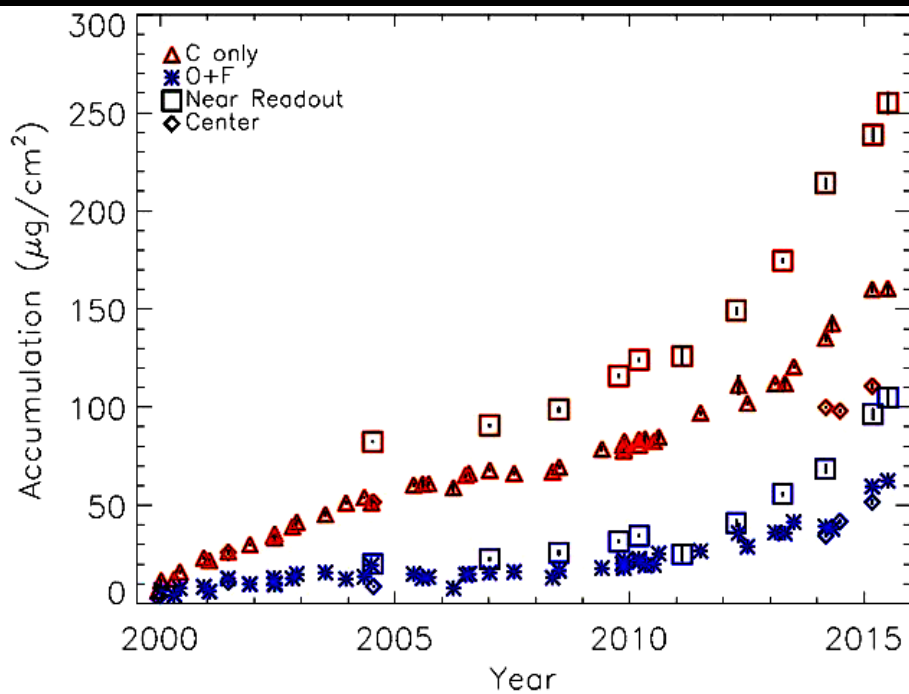


# Evolution of mass column, its rate, and composition



- Accumulation of contaminants
  - LETG/ACIS-S spectra
    - Atomic (C,O,F) edge depths
  - Thickest near OBF edges

- Rate fell until about 2009 then started rising.
- Composition changes indicate multiple species.





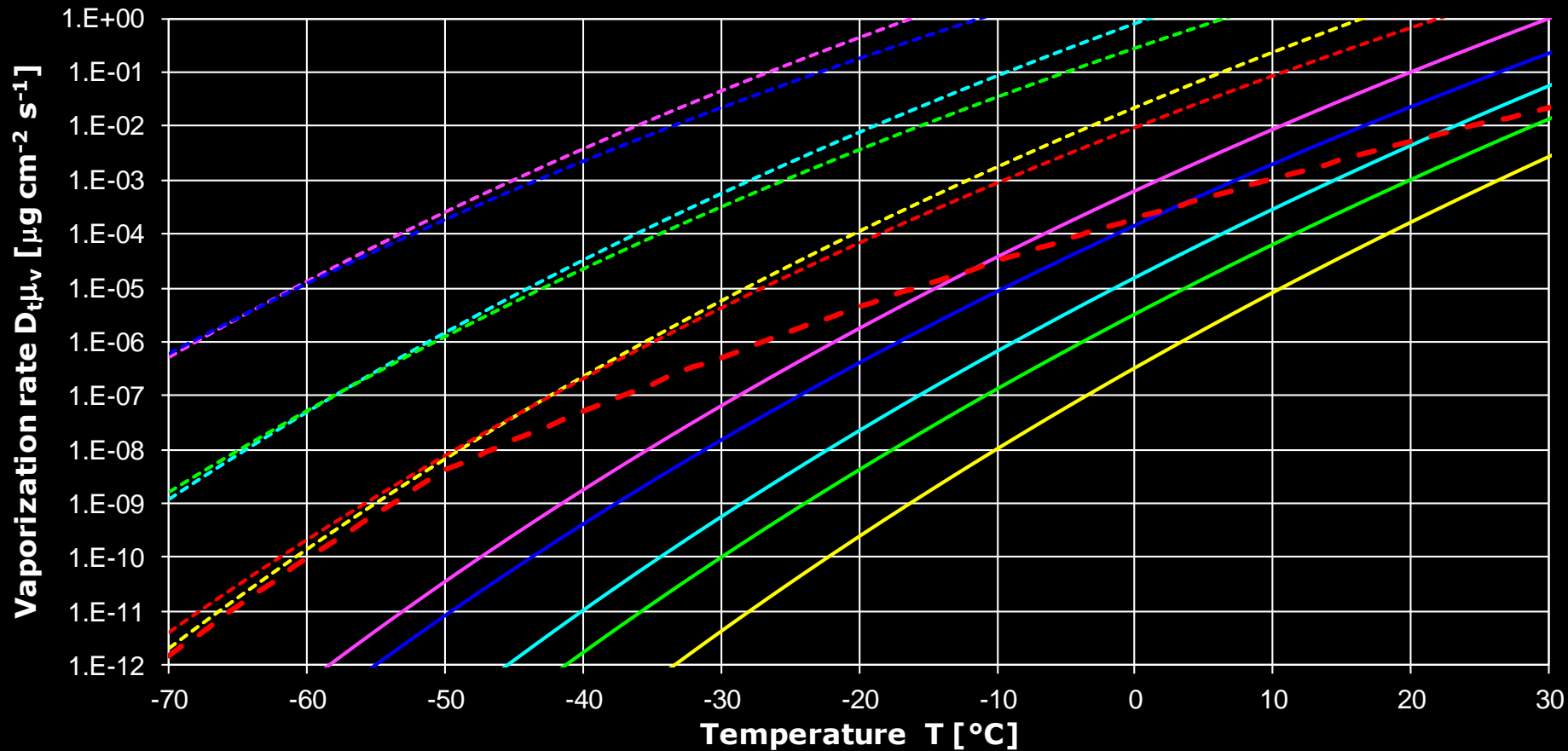


# Temperature dependence of mass vaporization rate



## Mass vaporization rates of some organic compounds

tetradecane pentadecane hexadecane heptadecane octadecane nonadecane  
eicosane heneicosane docosane tricosane tetracosane DOP

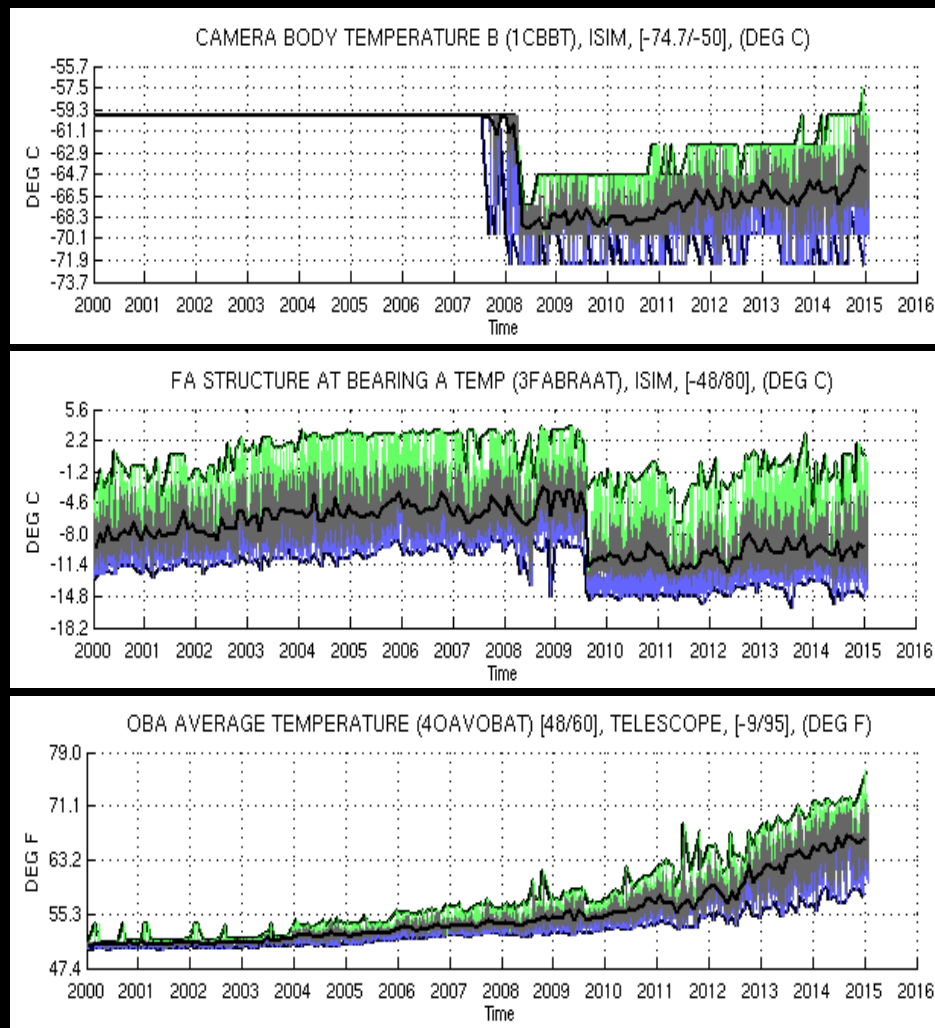




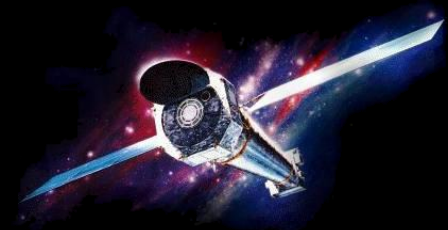
# Thermal history



- Most systems are warming.
  - ❑ Continuing degradation of external insulation (MLI)
- Strive to keep ACIS focal plane cold to preserve performance.
  - ❑ Carefully plan observations.
  - ❑ Disabled some heaters.
    - ACIS detector-housing heater (2008 April)
    - A SIM focus-assembly heater (2009 August)
- Optical bench has warmed rapidly since about 2010.
  - ❑ New contamination source?







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# ACIS geometric model (interior view)

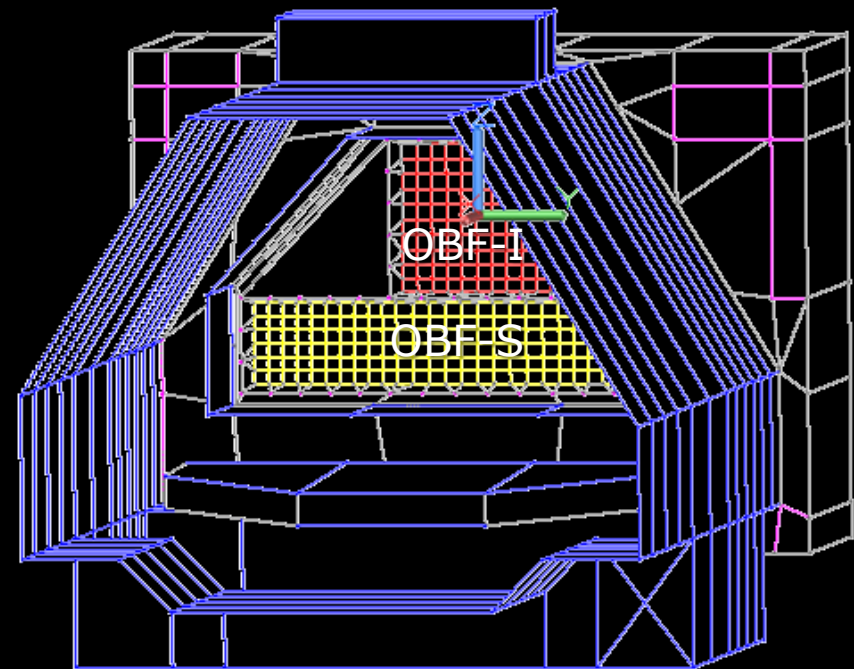
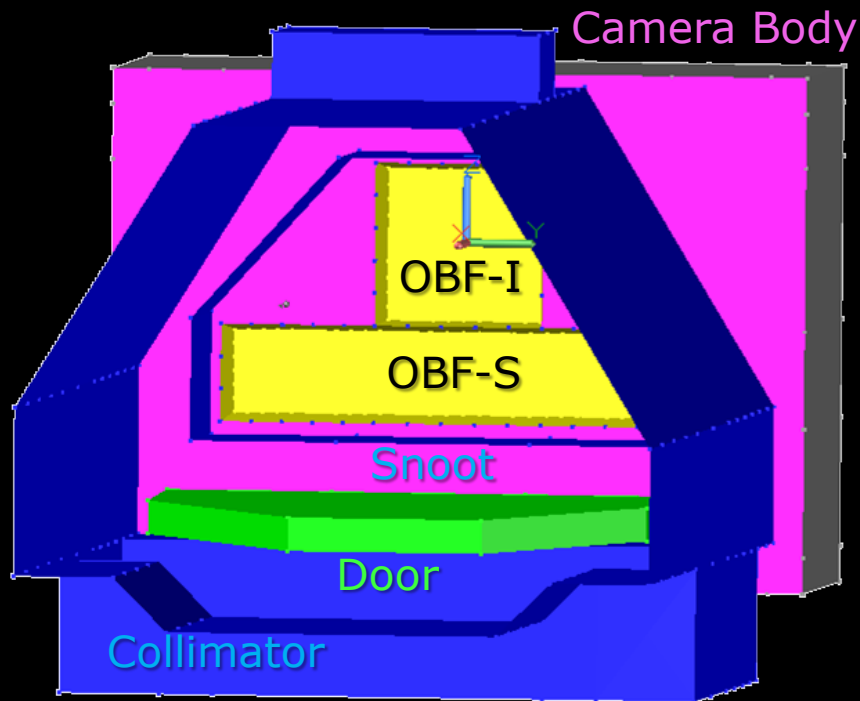


## ➤ Interior view of ACIS cavity

- ❑ Snoot & door inside collimator
- ❑ Camera top with OBFs

## ❑ High-resolution model maps temperature gradients

- OBF: 121 I & 203 S nodes
- Collimator: 12 axial zones



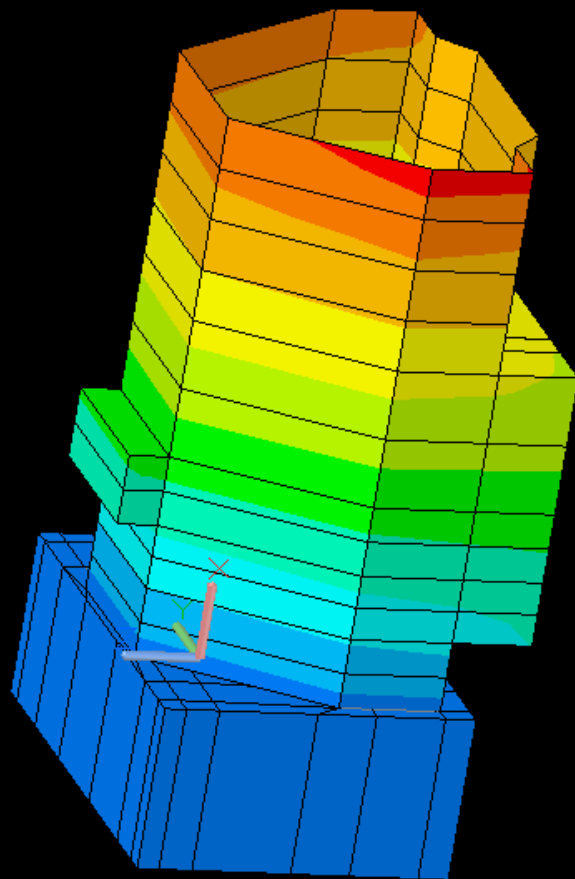


# ACIS temperature distribution (operational conditions)

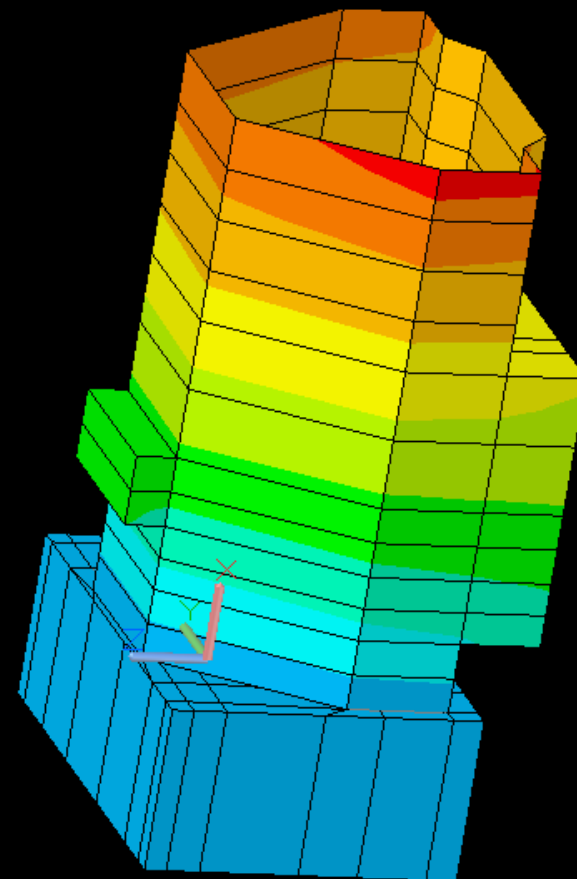
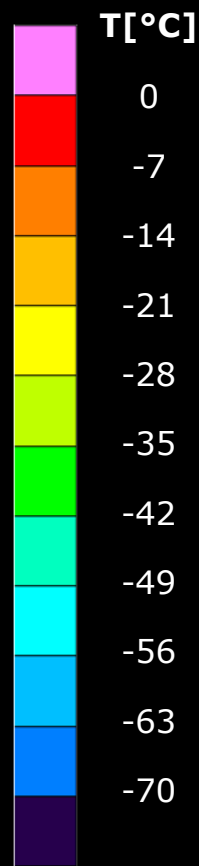


➤ DH heater OFF,  $T_{FP} = -120^{\circ}\text{C}$

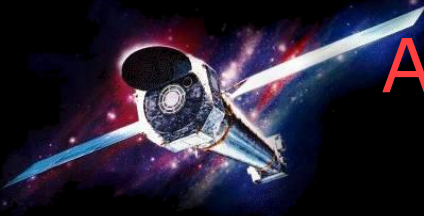
➤  $T_{DH} = -60^{\circ}\text{C}$ ,  $T_{FP} = -120^{\circ}\text{C}$



$\epsilon_{\text{OBF}} = 0.40$



$\epsilon_{\text{OBF}} = 0.40$

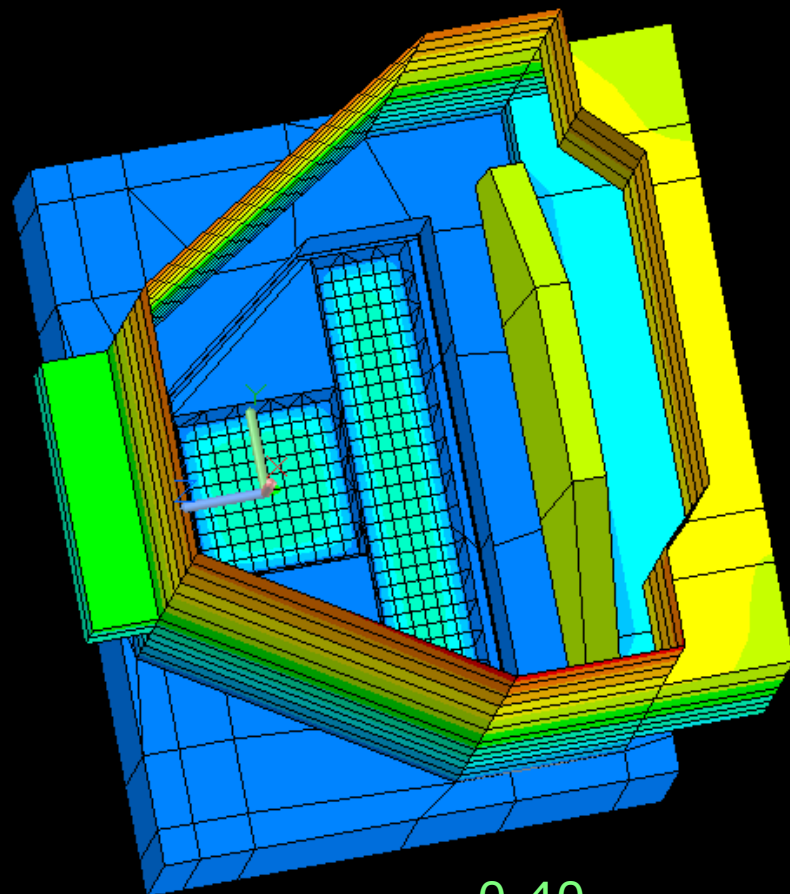


# ACIS temperature distribution (operational conditions)

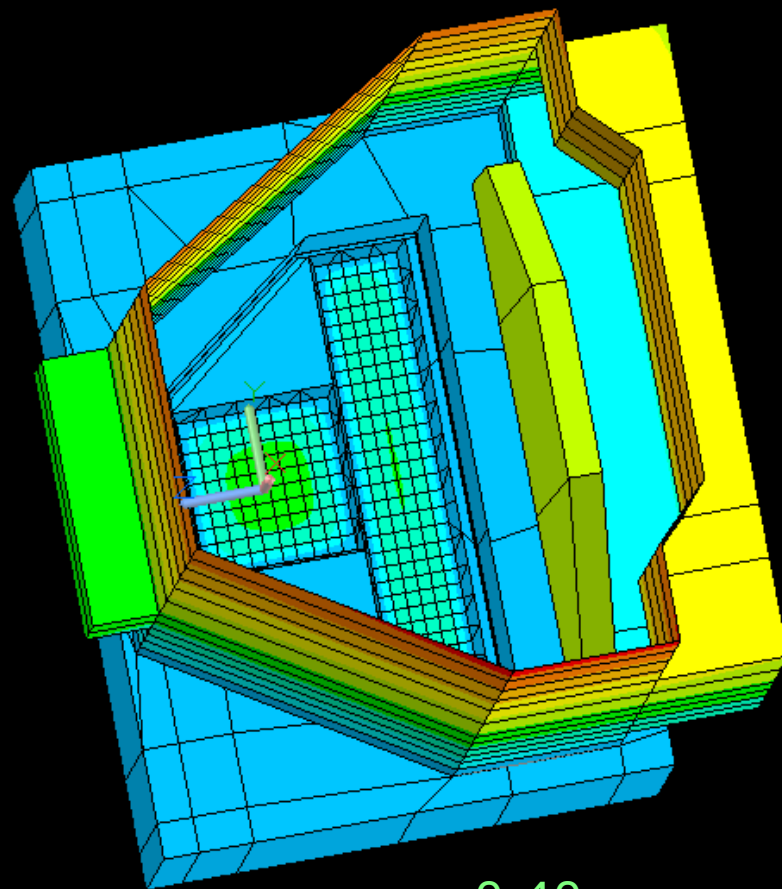
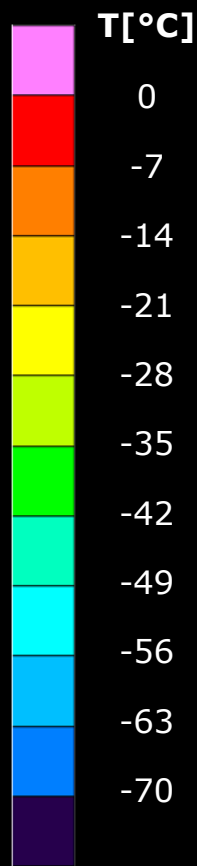


➤ DH heater OFF,  $T_{FP} = -120^{\circ}\text{C}$

➤  $T_{DH} = -60^{\circ}\text{C}$ ,  $T_{FP} = -120^{\circ}\text{C}$



$\epsilon_{OBF} = 0.40$



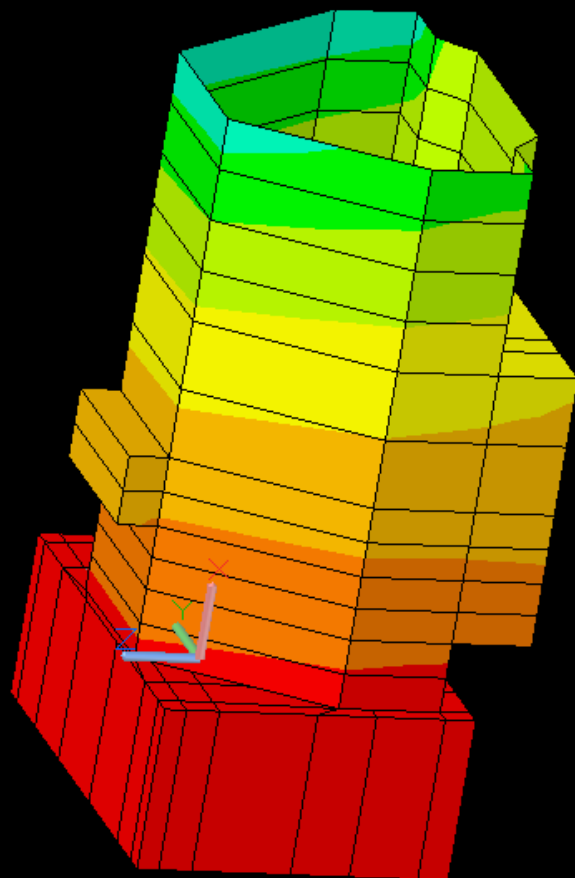
$\epsilon_{OBF} = 0.40$



# ACIS temperature distribution (bake-out conditions)

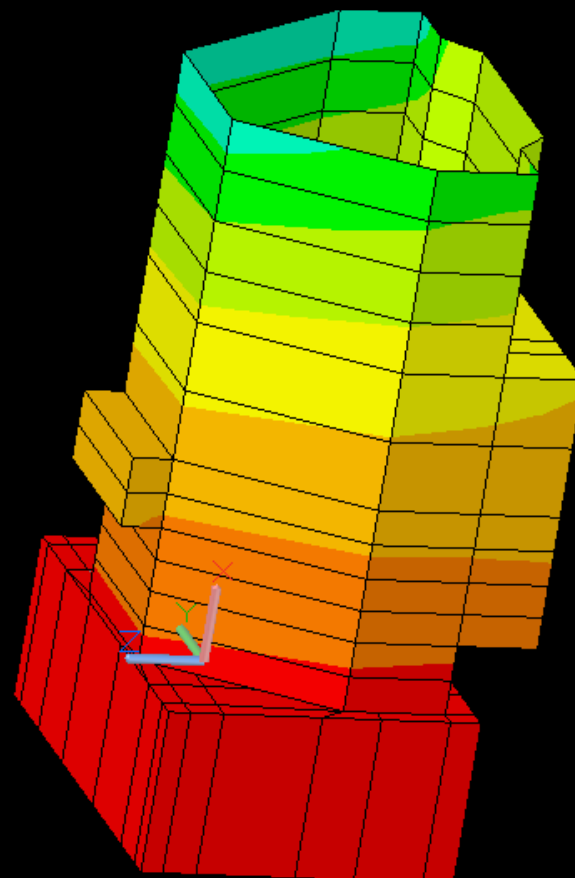


➤  $T_{DH} = +25^{\circ}\text{C}$ ,  $T_{FP} = -60^{\circ}\text{C}$



$\epsilon_{OBF} = 0.40$

➤  $T_{DH} = +25^{\circ}\text{C}$ ,  $T_{FP} = +25^{\circ}\text{C}$



$\epsilon_{OBF} = 0.40$

$T[^{\circ}\text{C}]$

+25

+20

+15

+10

+5

0

-5

-10

-15

-20

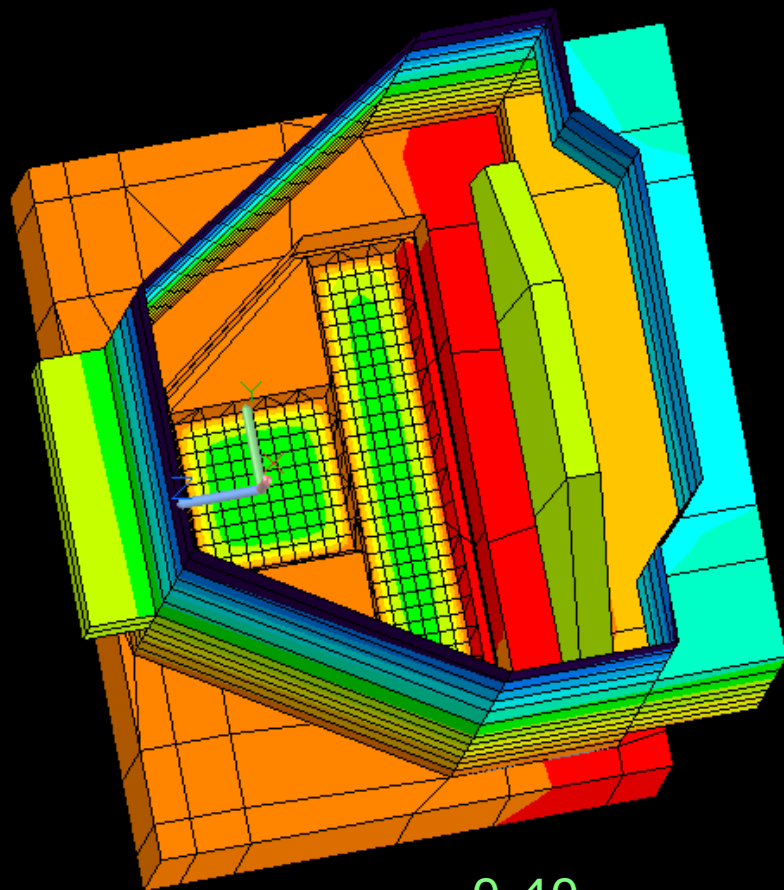
-25



# ACIS temperature distribution (bake-out conditions)

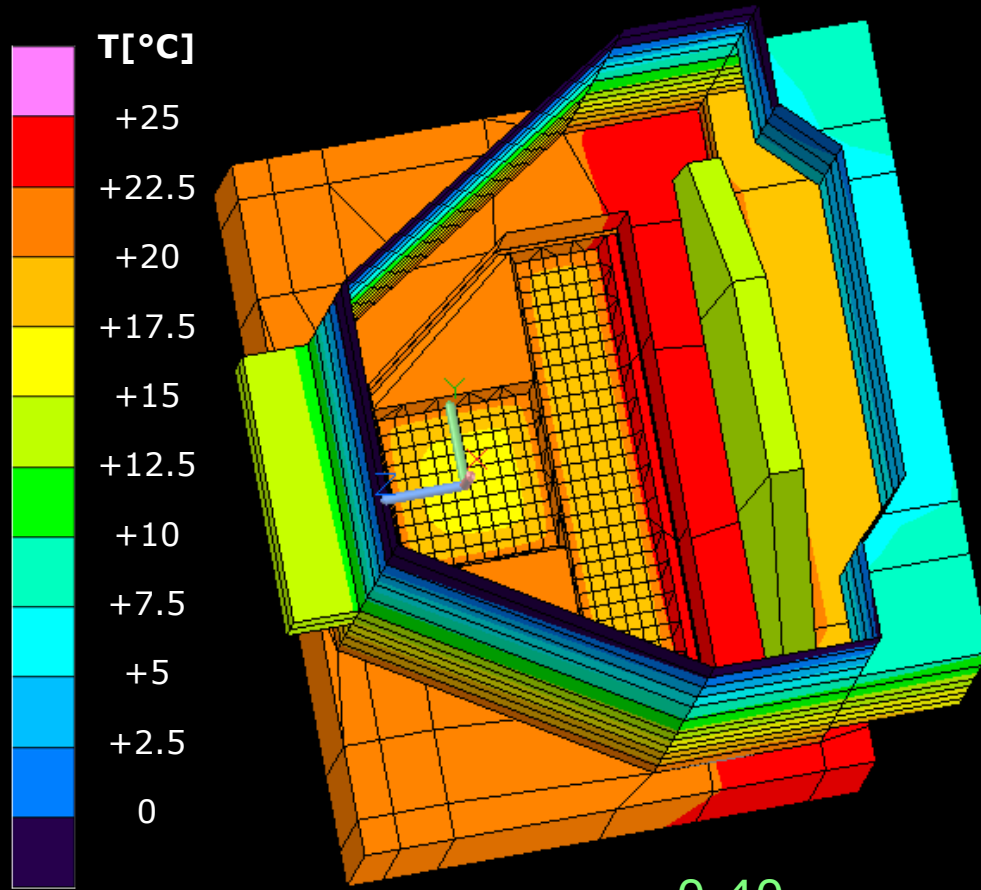


➤  $T_{DH} = +25^{\circ}\text{C}$ ,  $T_{FP} = -60^{\circ}\text{C}$



$\epsilon_{\text{OBF}} = 0.40$

➤  $T_{DH} = +25^{\circ}\text{C}$ ,  $T_{FP} = +25^{\circ}\text{C}$



$\epsilon_{\text{OBF}} = 0.40$

$T[^{\circ}\text{C}]$

+25

+22.5

+20

+17.5

+15

+12.5

+10

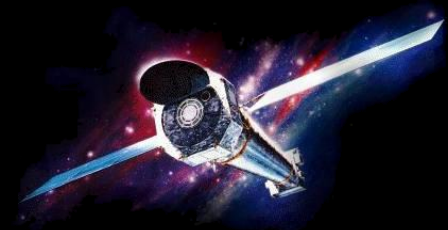
+7.5

+5

+2.5

0





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# Molecular flux equations and geometric view factors



## ➤ Net mass flux onto node j

$$\frac{d\mu_j}{dt} = -\dot{\mu}_v(T_j)\Theta(\mu_j) + \sum_k \dot{\mu}_v(T_k)\Theta(\mu_k) f_{jk} \frac{A_k}{A_j}$$

## ➤ Mass vaporization flux

❑ Related to vapor pressure

$$\dot{\mu}_v(T) = \frac{P_v(T)}{\sqrt{2\pi RT/M}}$$

## ➤ Clausius–Clapeyron relation

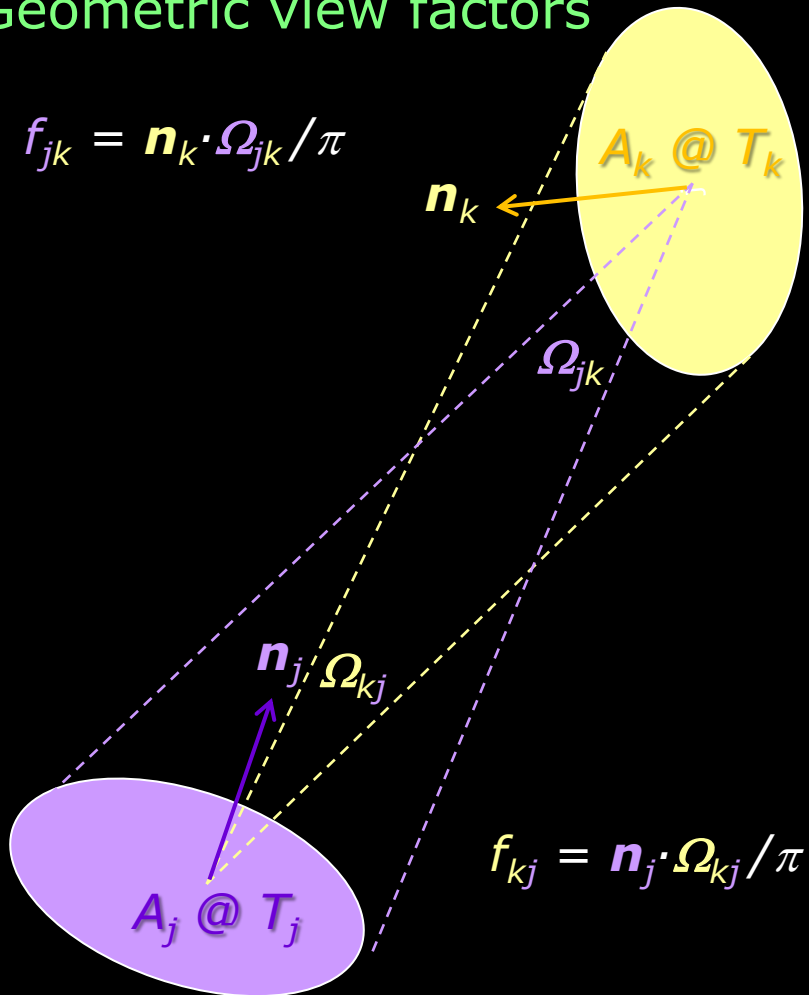
❑ Temperature dependence

❑ Vaporization enthalpy  $\Delta_v H$

$$P_v(T) = P_v(T_o) \text{Exp} \left[ -\frac{\Delta_v H}{R} \left( \frac{1}{T} - \frac{1}{T_o} \right) \right]$$

$$\dot{\mu}_v(T) = \dot{\mu}_v(T_o) \sqrt{\frac{T_o}{T}} \text{Exp} \left[ -\frac{\Delta_v H}{R} \left( \frac{1}{T} - \frac{1}{T_o} \right) \right]$$

## ➤ Geometric view factors





# Simulations of contaminant accumulation onto ACIS OBFs



## ➤ Lower volatility contaminant

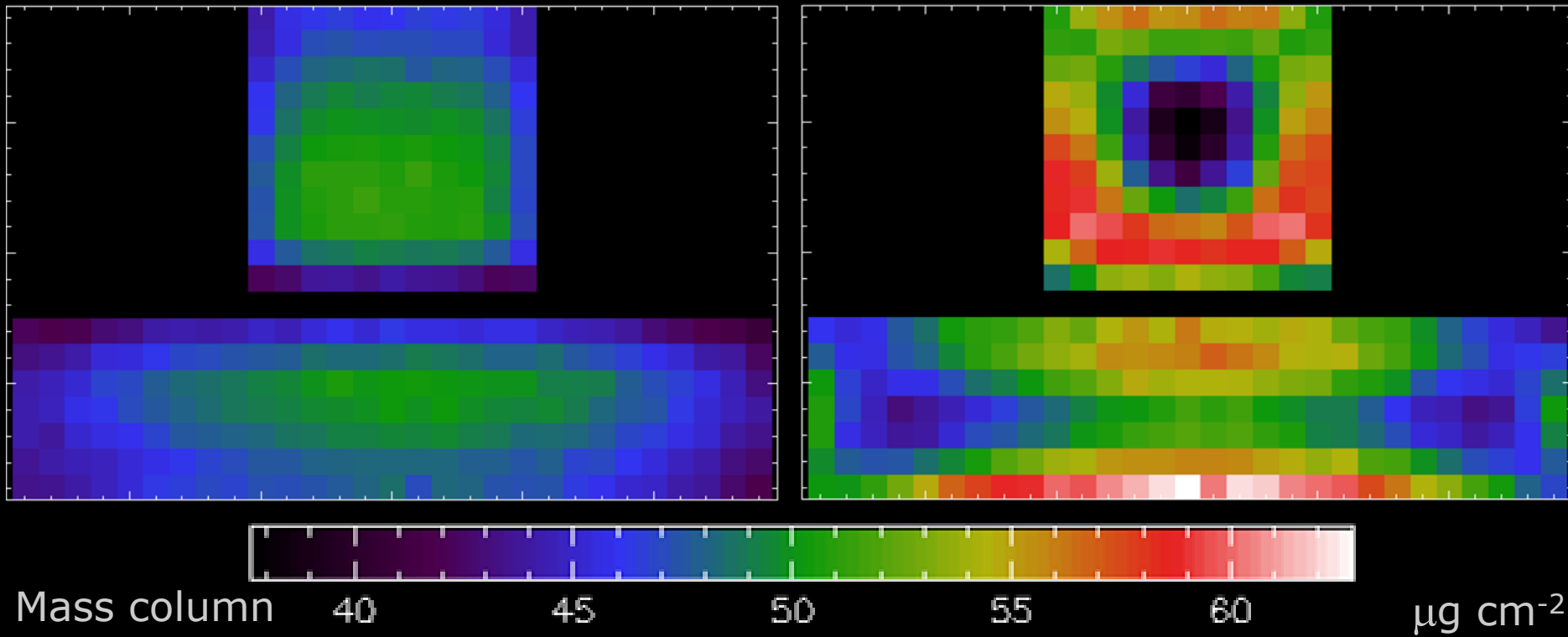
□ Deposition dominates.

○ Accumulates most at center.

## ➤ Higher volatility contaminant

□ Vaporization is significant.

○ Accumulates most at edges.





# Accumulation simulation: two components

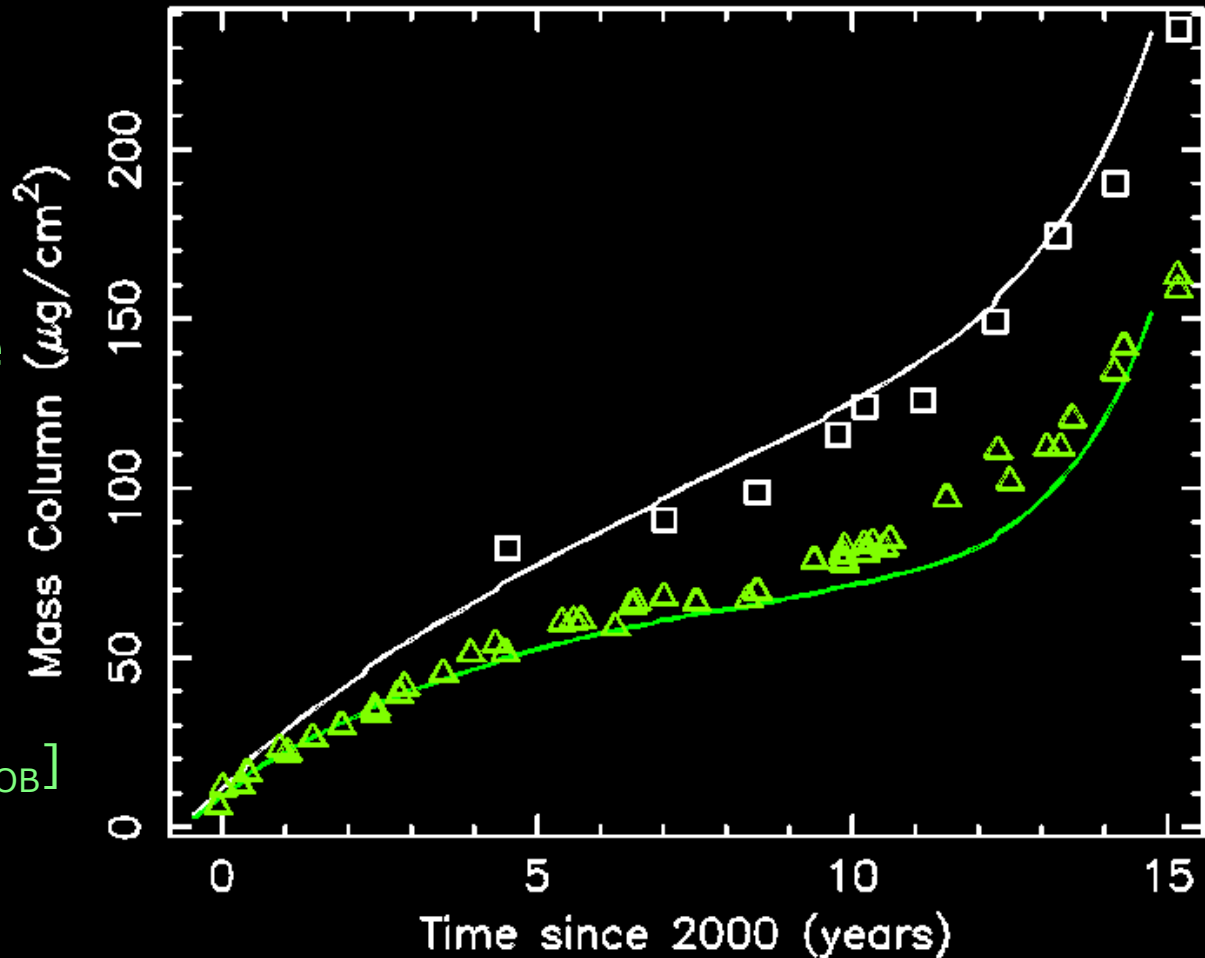


## ➤ Low-volatility component

- Source rate drops exponentially due to depletion.
  - 3.7-year timescale

## ➤ Medium-volatility component

- Source rate rises with increasing optical-bench  $T_{OB}$ .
  - $\propto \text{Exp}[-\text{constant}/T_{OB}]$
  - Rises until source depletion occurs.

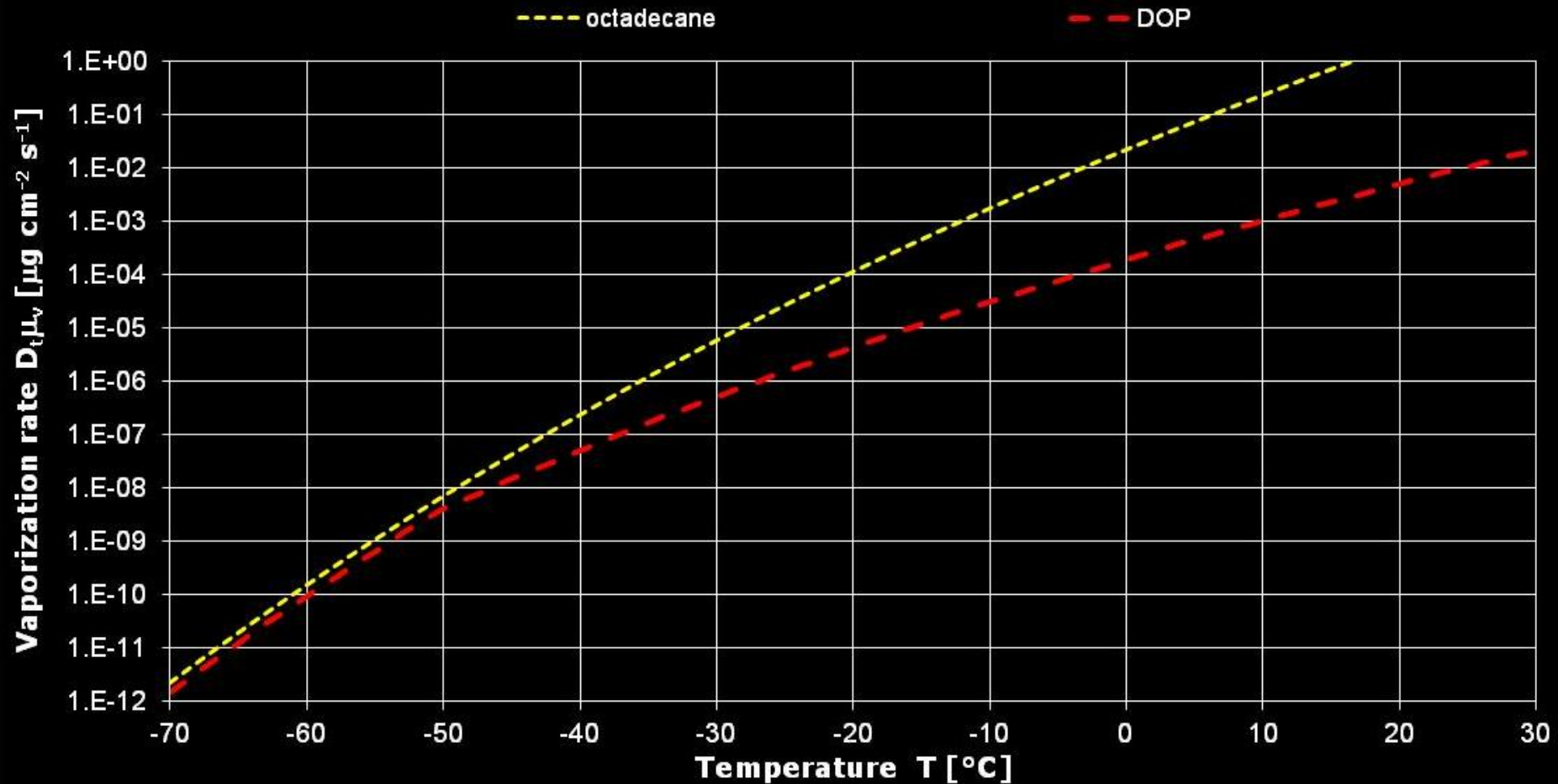




# Vaporization rate: Dependence upon phase state



## Mass vaporization rates of a solid and of a liquid





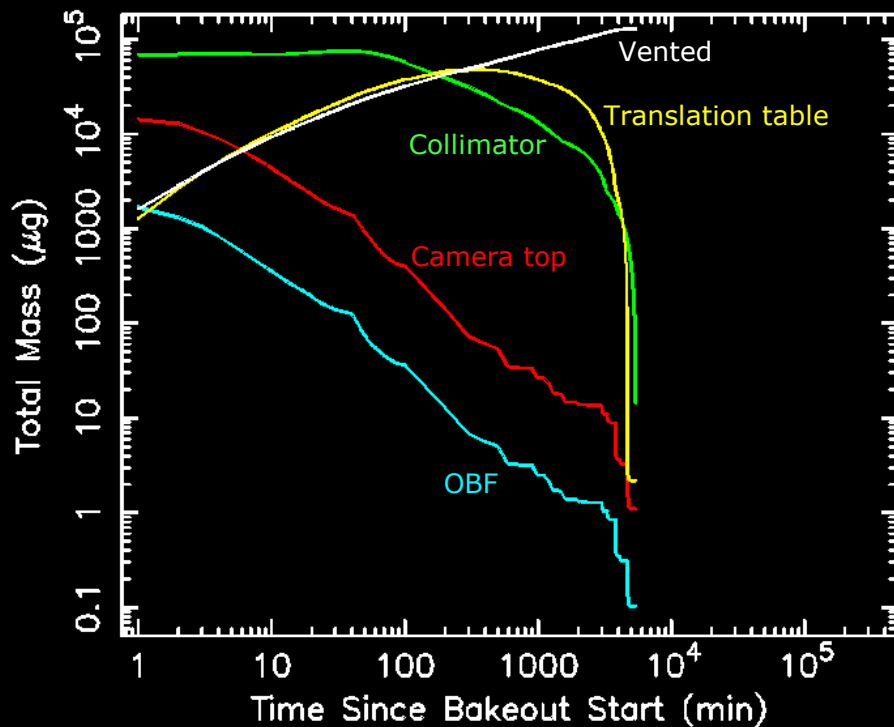
# Bake-out simulation: Octadecane mass



## ➤ Warm focal plane

$$\square T_{DH} = +25^{\circ}\text{C}$$

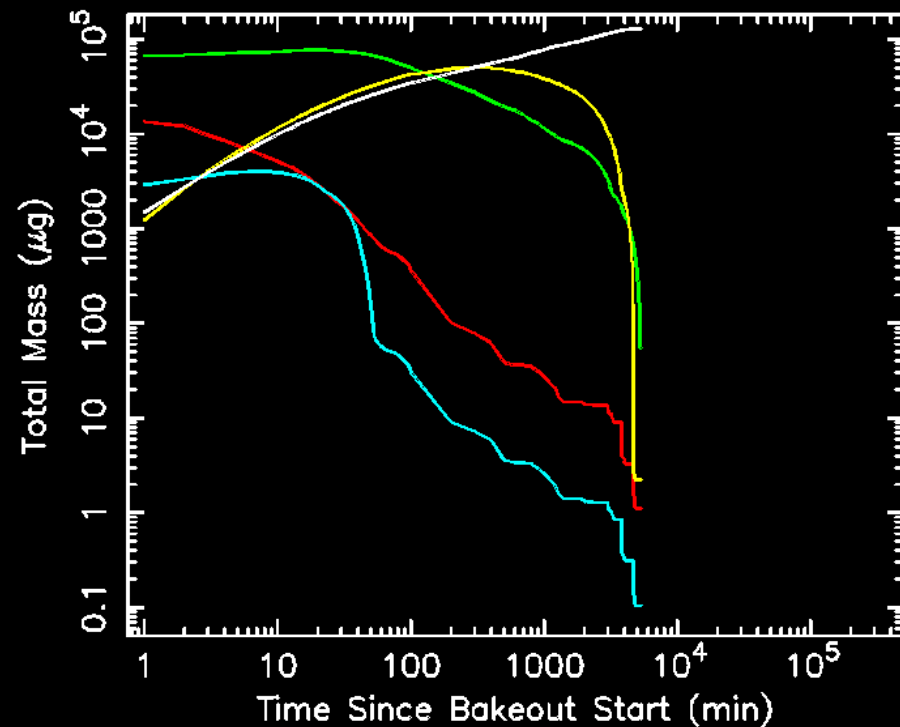
$$\square T_{FP} = +25^{\circ}\text{C}$$



## ➤ Cool focal plane

$$\square T_{DH} = +25^{\circ}\text{C}$$

$$\square T_{FP} = -60^{\circ}\text{C}$$







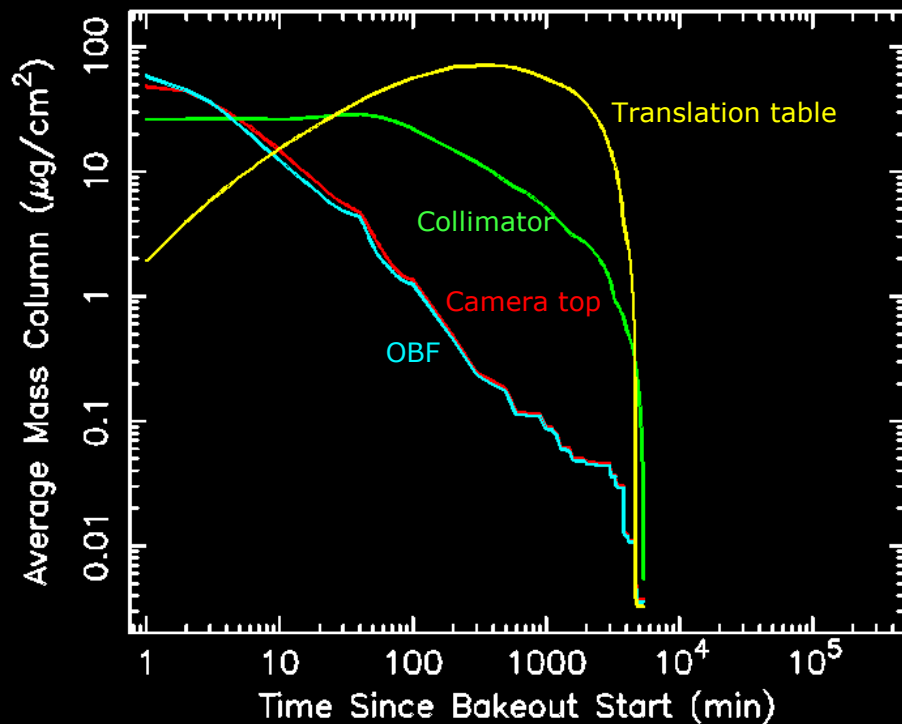
# Bake-out simulation: Octadecane column



## ➤ Warm focal plane

□  $T_{DH} = +25^{\circ}\text{C}$

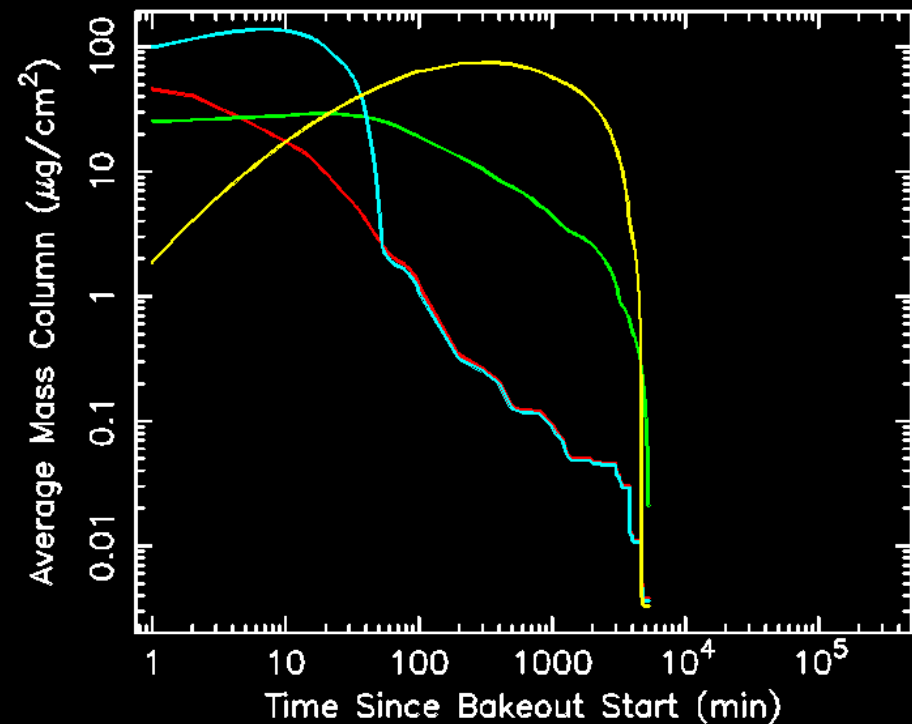
□  $T_{FP} = +25^{\circ}\text{C}$



## ➤ Cool focal plane

□  $T_{DH} = +25^{\circ}\text{C}$

□  $T_{FP} = -60^{\circ}\text{C}$





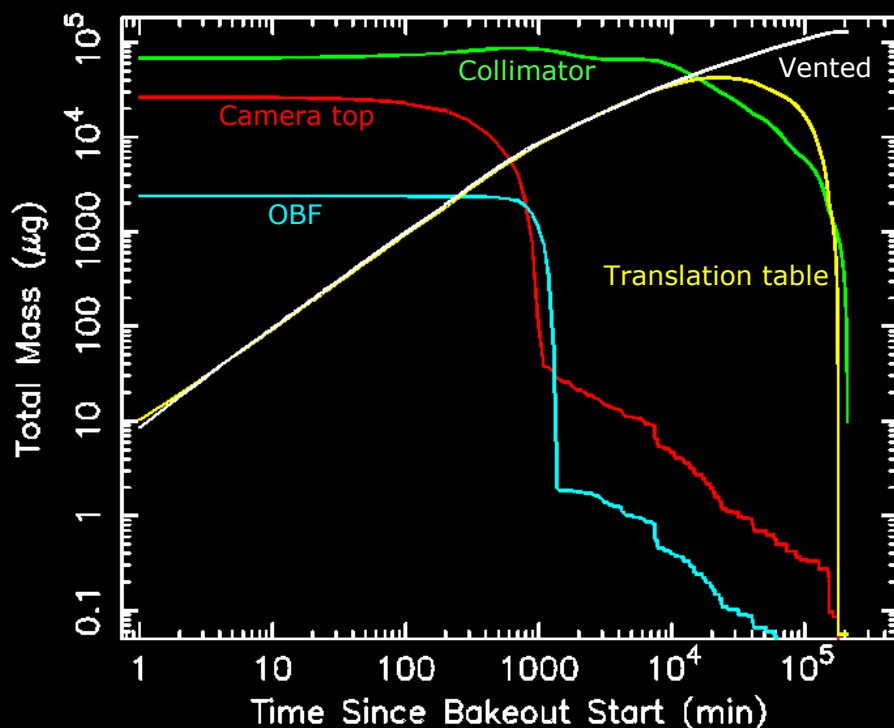
# Bake-out simulation: Dioctyl phthalate mass



## ➤ Warm focal plane

$$\square T_{DH} = +25^{\circ}\text{C}$$

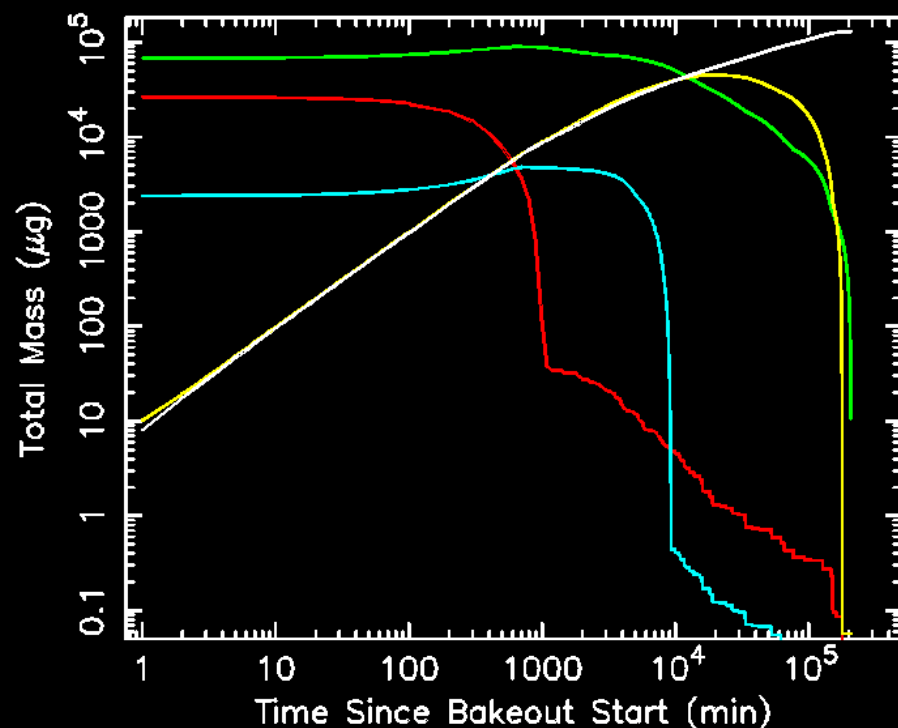
$$\square T_{FP} = +25^{\circ}\text{C}$$



## ➤ Cool focal plane

$$\square T_{DH} = +25^{\circ}\text{C}$$

$$\square T_{FP} = -60^{\circ}\text{C}$$





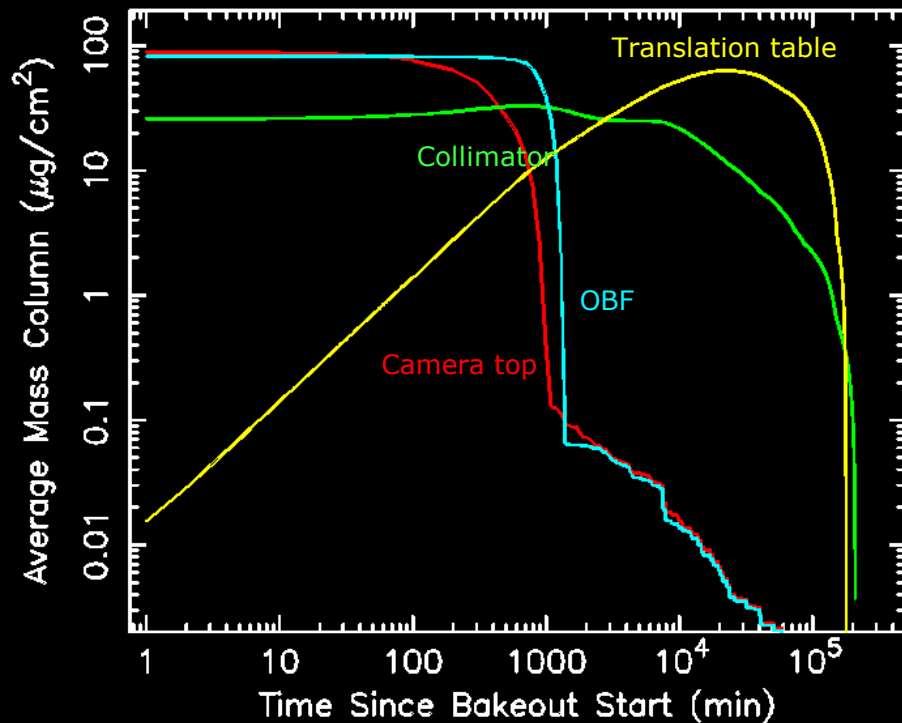
# Bake-out simulation: Dioctyl phthalate column



## ➤ Warm focal plane

□  $T_{DH} = +25^{\circ}\text{C}$

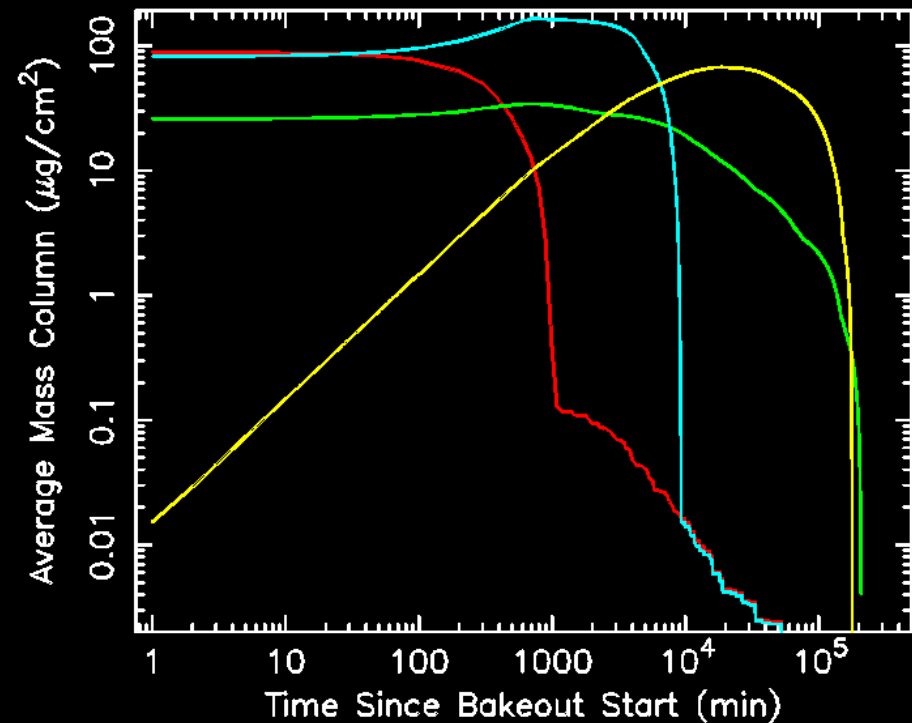
□  $T_{FP} = +25^{\circ}\text{C}$

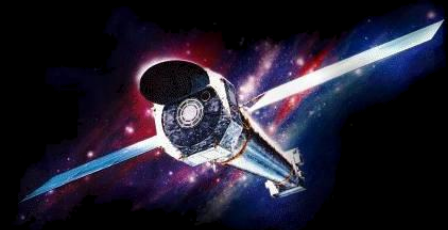


## ➤ Cool focal plane

□  $T_{DH} = +25^{\circ}\text{C}$

□  $T_{FP} = -60^{\circ}\text{C}$





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# Summary



- Contamination-migration simulation provides a useful tool.
  - ❑ Utility for absolute predictions is still limited.
    - Absolute predictions require knowledge of contaminant's volatility.
    - Uncertainty in temperatures propagates exponentially to rate error.
  - ❑ Model may require additional physics.
    - Treatment of multiple molecular species
    - Dependence of thermal emissivity upon contaminant mass column
      - Affects temperature distribution and thus mass vaporization rate
    - Surface redistribution, especially for a liquid contaminant
- Will use model to provide input for a bake-out decision.
  - ❑ Constrain properties of molecular contaminant(s).
  - ❑ Simulate contamination migration under potential scenarios.
    - Turning housing heaters back ON
    - Various bake-out conditions for ACIS